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# ***Optical System Alignment, Tolerancing, and Verification VII***

**José Sasián  
Richard N. Youngworth**  
*Editors*

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The CID Number appears on each page of the manuscript. The complete citation is used on the first page, and an abbreviated version on subsequent pages. Numbers in the index correspond to the last two digits of the six-digit CID Number.

# Contents

v	Conference Committee
vii	Introduction

---

## SESSION 1 TOLERANCING AND INSTRUMENT ALIGNMENT

---

- 8844 02 **Optomechanical considerations for realistic tolerancing** [8844-1]  
E. Herman, J. Sasián, College of Optical Sciences, The Univ. of Arizona (United States);  
R. N. Youngworth, Riyo LLC (United States)
- 8844 03 **Alignment of four-mirror wide field corrector for the Hobby-Eberly Telescope (Invited Paper)** [8844-2]  
C. J. Oh, E. H. Frater, L. Coyle, M. Dubin, A. Lowman, C. Zhao, J. H. Burge, College of  
Optical Sciences, The Univ. of Arizona (United States)
- 8844 04 **Secondary color correction and tolerance sensitivity: What can you get away with? (Invited Paper)** [8844-3]  
J. R. Rogers, Synopsys, Inc. (United States)

---

## SESSION 2 ALIGNMENT AND OPTOMECHANICS

---

- 8844 06 **Optical alignment of the Global Precipitation Measurements (GPM) star trackers** [8844-5]  
S. Hetherington, NASA Goddard Space Flight Ctr. (United States); D. Osgood, J. McMann,  
V. Roberts, J. Gill, K. McLean, Qinetiq North America (United States)
- 8844 07 **Method of calculation and tables of optothermal coefficients and thermal diffusivities for glass** [8844-22]  
D. Reshidko, J. Sasián, College of Optical Sciences, The Univ. of Arizona (United States)
- 8844 08 **Integration and alignment of ATLAS instrument engineering model components in Optical Development System Lab** [8844-7]  
T. Evans, SGT, Inc. (United States)
- 8844 09 **High-power laser parabola focus modelling at the Central Laser Facility** [8844-9]  
R. I. Heathcote, R. J. Clarke, T. B. Winstone, J. S. Green, Rutherford Appleton Lab. (United Kingdom)

---

**SESSION 3      ALIGNMENT, TESTING, AND ELECTRO-OPTICS**

---

- 8844 0A      **Alignment and testing of a telecentric zoom lens used for the Cygnus x-ray source** [8844-11]  
R. M. Malone, S. A. Baker, K. K. Brown, J. J. Castaneda, A. H. Curtis, National Security Technologies, LLC (United States); J. Danielson, Los Alamos National Lab. (United States); D. W. Droemer, D. L. Esquibel, National Security Technologies, LLC (United States); T. J. Haines, Los Alamos National Lab. (United States); J. S. Hollabaugh, R. A. Howe, J. A. Huerta, M. I. Kaufman, National Security Technologies, LLC (United States); N. S. P. King, Los Alamos National Lab. (United States); S. S. Lutz, K. D. McGillivray, A. Smith, B. M. Stokes, A. Tibbitts, National Security Technologies, LLC (United States)
- 8844 0B      **Double Zernike polynomial and its application in optical alignment** [8844-12]  
M.-S. Tsao, C.-W. Liang, National Central Univ. (Taiwan)
- 8844 0C      **FDTD modeling of chip-to-chip waveguide coupling via optical quilt packaging** [8844-13]  
T. Ahmed, Univ. of Notre Dame (United States); T. Butler, Univ. of Notre Dame (United States) and Cork Institute of Technology (Ireland); A. A. Khan, Univ. of Notre Dame (United States); J. M. Kulick, Indiana Integrated Circuits (United States); G. H. Bernstein, A. J. Hoffman, S. S. Howard, Univ. of Notre Dame (United States)
- 8844 0D      **Modified point diffraction interferometer to evaluate tolerances in the design of progressive addition lenses** [8844-14]  
S. Chamadoira, Univ. de Santiago de Compostela (Spain); J. Sasian, College of Optical Sciences, The Univ. of Arizona (United States); E. Acosta, Univ. de Santiago de Compostela (Spain)

---

**SESSION 4      VERIFICATION OF OPTICAL SYSTEMS**

---

- 8844 0E      **Discrepancies when analyzing and testing high aperture lenses with pupil aberration** [8844-15]  
J. R. Mulley, Melles Griot (United States)
- 8844 0F      **Highly accurate measurement of lens surface distances within optical assemblies for quality testing** [8844-16]  
P. Langehanenberg, A. Ruprecht, D. Off, B. Lueerss, TRIOPTICS GmbH (Germany)
- 8844 0G      **A new approach for the verification of optical systems** [8844-17]  
U. Siddique, V. Aravantinos, S. Tahar, Concordia Univ. (Canada)
- 8844 0H      **The contribution of optical methods and geodetic instruments in structural monitoring: a brief historical survey** [8844-18]  
G. M. T. Radulescu, A. T. G. Radulescu, Technical Univ. of Cluj Napoca (Romania)
- 8844 0I      **Development of a medium-size SWIR imaging telescope: integration, calibration, and MTF measurement** [8844-20]  
O. Yilmaz, O. Selimoglu, F. Turk, TÜBİTAK UZAY (Turkey)

*Author Index*

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# Introduction

"Unfortunately, alignment is often considered only when one confronts the hardware. This is often too late, since system constraints have been determined."

Richard N. Shagam (Cochair of Optical Alignment), SPIE Volume 251, 1980

This year marked the seventh time this annual conference has taken place in beautiful San Diego, California, USA at SPIE Optics + Photonics 2013. This year's Optical System Alignment, Tolerancing and Verification VII conference was again very successful. The conference consisted of a day of high quality presentations, the poster session, and subsequent proceedings articles. Specifically, this year the conference had four strong sessions on tolerancing and instrument alignment, alignment and optomechanics, alignment testing and electro-optics, and verification of optical systems. We sincerely thank our invited speakers, contributed speakers, poster paper presenters, and the superb community for making the sessions and conference such a success. It is very clear that the topics covered by this conference continue to be of great interest to the optics and photonics community.

The history of SPIE conferences on Optical Alignment dates back to 1980. The most recent embodiment started in 2007 by José Sasián and Mitch Ruda. The listing of years and conference chairs for optical alignment (to 1993), optical system alignment and tolerancing (2007 to 2008), and, finally, addition of the topic of verification (2009-present) are:

- 1980 Richard N. Shagam and William C. Sweatt
- 1984 Mitch Ruda
- 1986 Mitch Ruda
- 1993 Mitch Ruda
- 2007 J. Sasián and M. Ruda
- 2008 J. Sasián and R. N. Youngworth
- 2009 J. Sasián and R. N. Youngworth
- 2010 J. Sasián and R. N. Youngworth
- 2011 J. Sasián and R. N. Youngworth
- 2012 J. Sasián and R. N. Youngworth
- 2013 J. Sasián and R. N. Youngworth

We must of course thank our excellent program committee for continuing to promote this conference. Furthermore, we are once again quite grateful to the greater community for sharing work and participating, as interaction in this area is very beneficial in advancing our field. Finally, we thank the volunteers and SPIE staff for providing us the opportunity to cover the subjects of optical system

alignment, tolerancing, and verification in a dedicated conference and proceedings.

This conference will continue in 2014. We encourage everyone interested in optical system alignment, tolerancing, and verification to look for the call for papers and to submit your work in early 2014. Please feel free to contact us or anyone on our program committee if you have any questions.

Finally, and most importantly in our hearts, is to mark the passing of one of the true and pure greats in the optics community, Dr. Mitch Ruda. Mitch was absolutely essential in the formation of this conference and served with us for a number of years to help highlight the importance of optical alignment. Many of us have known Mitch, worked with him, learned from him, and admired his very strong body of work. He will be greatly missed by the entire optics community.

**José Sasián**  
**Richard N. Youngworth**